

UNITED STATES PATENT AND TRADEMARK OFFICE  
**CERTIFICATE OF CORRECTION**

PATENT NO. : 7,053,001 B2  
APPLICATION NO. : 10/676983  
DATED : May 30, 2006  
INVENTOR(S) : Tingkai Li et al.

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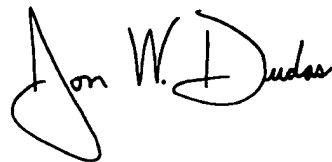
It is certified that error appears in the above-identified patent and that said Letters Patent is hereby corrected as shown below:

Column 5, line 29 insert the following:

15. The method of claim 7 wherein the etching chamber pressure is maintained at a pressure of about 6 mtorr; and wherein BCl is delivered at a flow rate of about 30 sccm, and Cl is delivered at a flow rate of about 60 sccm, providing a gas volume of Cl which is twice that of BCl.

Signed and Sealed this

Nineteenth Day of February, 2008

A handwritten signature in black ink, appearing to read "Jon W. Dudas". The signature is stylized with a large, looped initial "J" and a cursive "Dudas".

JON W. DUDAS  
*Director of the United States Patent and Trademark Office*